Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1312	(metal adj layer) with silicid\$6 with anneal\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/09 08:17
L2	158	1 and ((dope\$4 or implant\$5) ion transistor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:05
L3	24	2 and inhibit\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT;	WITH	ON	2006/03/09 09:09
S T.			IBM_TDB		e de la compansión de l	
L4	5	2 and (inhibit\$4 adj2 ion)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 08:33
L8	1312	((metal adj layer) with silicid\$6 with anneal\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM IDB	OR	ON T	2006/03/09 08:56
L9	16	L8 and (remov\$4 unsilicid\$4 metal)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2006/03/09 08:56
L10	3	9 and ((dope\$4 or implant\$5) (ion or \$2nitrogen or hydrogen or fluorine) transistor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:14
L11	1	2 and ((dope\$4 or implant\$5) inhibit\$4 (ion or \$2nitrogen or hydrogen or fluorine) transistor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:04
L12	1631621	semiconductor	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:07

L13	187	12 and (metal inhibit\$4 silicide)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON .	2006/03/09 09:54
L14 .	20	13 and ((dope\$4 or implant\$5) (ion or \$2nitrogen or hydrogen or fluorine) transistor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	-2006/03/09 09:56
L15	1637	12 and (metal (prevent or inhibit\$4) silicide)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:55
L16	2270	12 and (metal (prevent\$4 or inhibit\$4) silicide)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM TDB	WITH	ON	2006/03/09 09:55
L17	259	16 and ((dope\$4 or implant\$5) (ion or \$2nitrogen or hydrogen or fluorine) transistor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:56
18	163	17 and anneal\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:56

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1312	(metal adj layer) with silicid\$6 with anneal\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/09 08:17
L2	158	1 and ((dope\$4 or implant\$5) ion transistor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:05
L3	24	2 and inhibit\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:09
L4	5	2 and (inhibit\$4 adj2 ion)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 08:33
L8	1312	((metal adj layer) with silicid\$6 with anneal\$4)	US-PGPUB; USPAT; EPO: JPO; DERWENT; IBM_TDB	OR.	ON-	2006/03/09 08:56
L9	16	L8 and (remov\$4 unsilicid\$4 metal)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2006/03/09 08:56
L10	3	9 and ((dope\$4 or implant\$5) (ion or \$2nitrogen or hydrogen or fluorine) transistor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:14
L11	1	2 and ((dope\$4 or implant\$5) inhibit\$4 (ion or \$2nitrogen or hydrogen or fluorine) transistor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:04
L12	1631621	semiconductor	US-PGPUB; USPAT;	WITH	ON	2006/03/09 09:07
			EPO; JPO; DERWENT; IBM_TDB			

3/9/06 9:35:43 AM C:\Documents and Settings\VYevsikov\My Documents\EAST\Workspaces\10797222.wsp

L13	. 187	12 and (metal inhibit\$4 silicide)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH .	ON .	2006/03/09 09:10
L14	20.	13 and ((dope\$4 or implant\$5) (ion or \$2nitrogen or hydrogen or fluorine) transistor)	US-PGPUB; USPAT; EPO; PO; DERWENT; IBM_TDB	WITH	ON	2006/03/09 09:14

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	769062	transistor	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR.	ON	2006/01/26 10:51
S2	5900	transistor with (metal adj layer)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON '	2006/01/26 10:53
S3	68	transistor with ((metal adj layer) with silicid\$6 with anneal\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/26 10:57
S4	1281	((metal adj layer) with silicid\$6 with anneal\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/26 10:58
S5	15	S4 and (remov\$4 unsilicid\$4 metal)	US PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2006/03/09 08:56
S6	11	S5 and (ion implant\$6)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/01/26 11:46
S7	12	S5 and (ion near3 implant\$6)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON #	2006/01/26 11:47
S8	7	S4 and (remov\$4 unsilicid\$4 metal)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON ·.	2006/01/26 11:47
S9 .	5	S8 and (ion near3 implant\$6)	US-PGPUB; USPAT; EPO; JPO;	ADJ	ON	2006/01/27 09:39
	7.		DERWENT; IBM_TDB			igi sa ¹⁸ s se til jalan sa Linguage

3/9/06 9:36:24 AM
C:\Documents and Settings\VYevsikov\My Documents\EAST\Workspaces\10797222.wsp

	f		T	T		
S10	5280	438/592,682,527,530,597,301.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON ·	2006/01/27 09:40
S11	490	S10 and (silicid\$6 near3 anneal\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT;	ADJ	ON	2006/01/27 09:42
+ 6			IBM_TDB			
S12	411	S11 and implant\$6	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/01/27 09:43
S13	31	S12 and (transistor with (metal adj layer))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/01/27 09:46
S14	12	S12 and (transistor with substrate with (metal adj layer))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/01/27 09:46
S15	69 €	transistor with (metal adj layer) with silicid\$6 with anneal\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/08 15:24
S16	1309	(metal adj layer) with silicid\$6 with anneal\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/09 08:17
S17	618	(deposit metal transistor)	US-PGPUB;	WITH S	ON	2006/03/08 15:25
			USPAT; EPO; JPO; DERWENT; IBM_TDB		的是一个 第二十二十二十二十二十二十二十二十二十二十二十二十二十二十二十二十二十二十二十	
S20	4	S17 and (silicid\$5 with (low adj temperature))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	WITH	ON	2006/03/08 15:29